BE VIII (BGS (CIRX) DC JECHTHOOF)

QP Coc

Time: 3 Hours. Sub! - Ic Technology QP Code: 31293

Max. Marks: 80

N.B.

1) Question No. 1 is compulsory

2) Solve any three questions from the remaining questions

3) Assume suitable data if necessary

1.	Solv	e any four of the following	(20)
		Explain Interstitial and substitutional diffusion process.	1
			7
	1100000	Explain the concept of clean rooms.	3.
	(d)	Explain Electronics package reliability. Explain the concept of clean rooms. Explain Nuclear and electronic stopping mechanisms in Ion implantation with neat diagrams Give the steps in a standard RCA cycle during wafer cleaning What is Ion Implantation? Explain the process with a neat diagram.	. Al
		diagrams	7
	(e)	Give the steps in a standard RCA cycle during wafer cleaning	6
		. 691	
2.		5	(4.0)
	(a)		
	(b)	Describe optical lithography with the help of a neat diagram.	(10)
	8905h.		
3.			
	(a)	Explain the fabrication process step along with vertical cross-sectional views for CMOS	
		Inverter using twin tub process.	(10)
	(b)	With neat diagram explain the Float Zone technique of crystal growth.	(10)
4.			
	(a)	What is the significance of Design rules? Drawlayout for the CMOS inverter using	(4.0)
		lambda (λ) based design rules.	(10)
	(b)	Discuss Etching methods for photoresists removal.	(10)
5.			(OF)
	(a)	Explain SOI fabrication using bonded SOI and smart cut method.	(05)
	(b)	State advantages of BICMOS over CMOS	(05)
	(c)	Describe with the help of a meat diagram Hayness-Schokley experiment for	(10)
	- 100	measurement of Drift Mobility of n-type semiconductor.	, ()
6	\\/rit	e short notes on anytour of the following	(20)
U.		MODFET and optoelectronics devices	N 085
	1000	Nanowire transistor	
		Molecular Beam epitaxy	
	(0)	Wolcould Deall opitall	

(d) Second order effects in bipolar transistor (e) VLST Technology Trends affecting Testing